

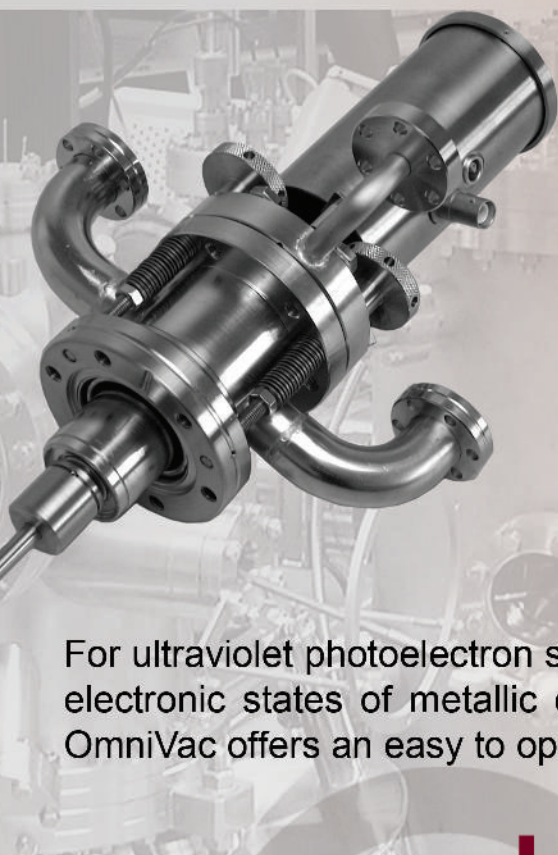


OmniVac

Surface Analysis and Vacuum Technology

Ultraviolet Source

UVS 200



For ultraviolet photoelectron spectroscopy of the occupied electronic states of metallic or semiconducting samples, OmniVac offers an easy to operate laboratory UV source.

- excellent and adjustable He I / He II ratio
- high photon flux / discharge current ratio
- small beam divergence $< \pm 1^\circ$
- differential pumping
- easy operation / ignition
- stable output
- high photon flux $< 1 \cdot 10^{15}$ ph/srs

www.omnivac.de

UVS 200 Ultraviolet Source

For ultraviolet photoelectron spectroscopy of the occupied electronic states of metallic or semiconducting samples, OmniVac offers an easy to operate laboratory UV source.

By adjusting the proper gas pressure in the discharge volume, the operator can choose different emission energies (e.g. 21,2 eV or 40,8 eV for He I / II). Also other gases like Ne or Xe can be used.

The **UVS 200** comes with a **PS-UVS 200** power supply.



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- ▶ high photon flux / discharge current ratio
- ▶ small beam divergence $< \pm 1^\circ$
- ▶ differential pumping
- ▶ easy operation / ignition
- ▶ stable output

UVS 200

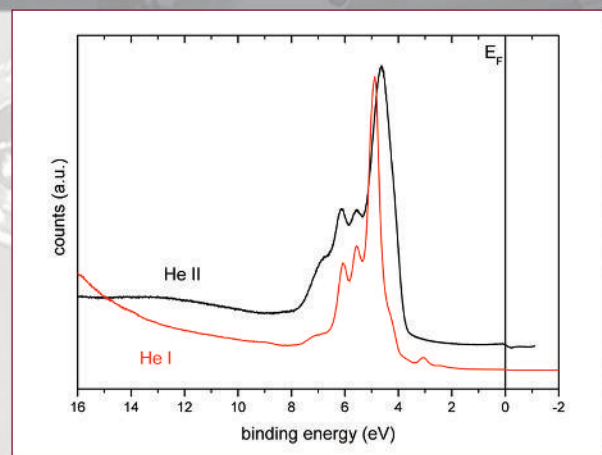
- 2-Stages differential pumping
- customized insertion length
- bakeable up to 250°C
- mounting flange CF 40

PS-UVS 200

- constant voltage or constant current mode
- easy ignition
- 19"x132 mm, 12 kg

Related products:

- PS-UVS 100 power supply
- leak valve (for gas inlet)
- pumping lines for differential pumping



He I- and He II spectra of a freshly annealed Ag thin film.



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